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The Environmental Footprint of Si Chip Manufacturing

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Imec

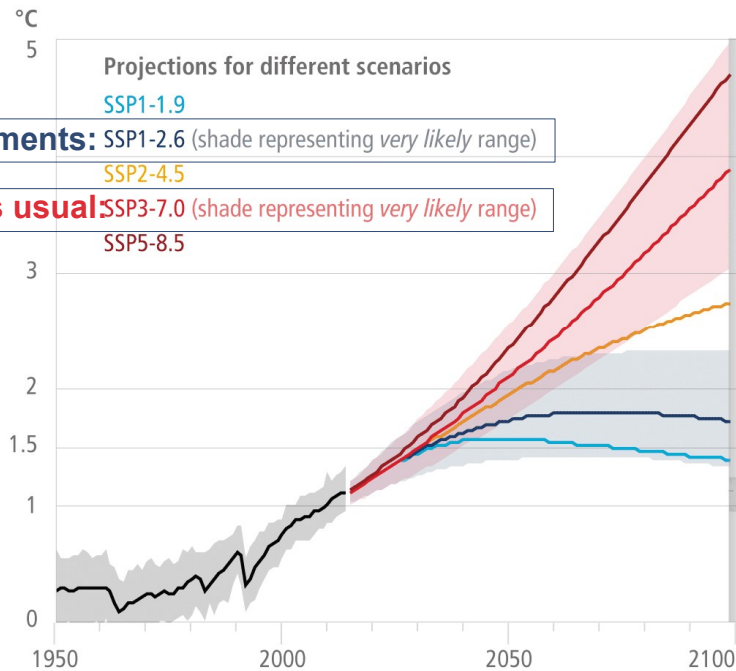
Cedric.Rolin@imec.be

Semicon Europa 2022
Smart and Green Manufacturing Summit
November 17, 2022

 semi™

Risks for increasing levels of global warming

Global surface temperature change



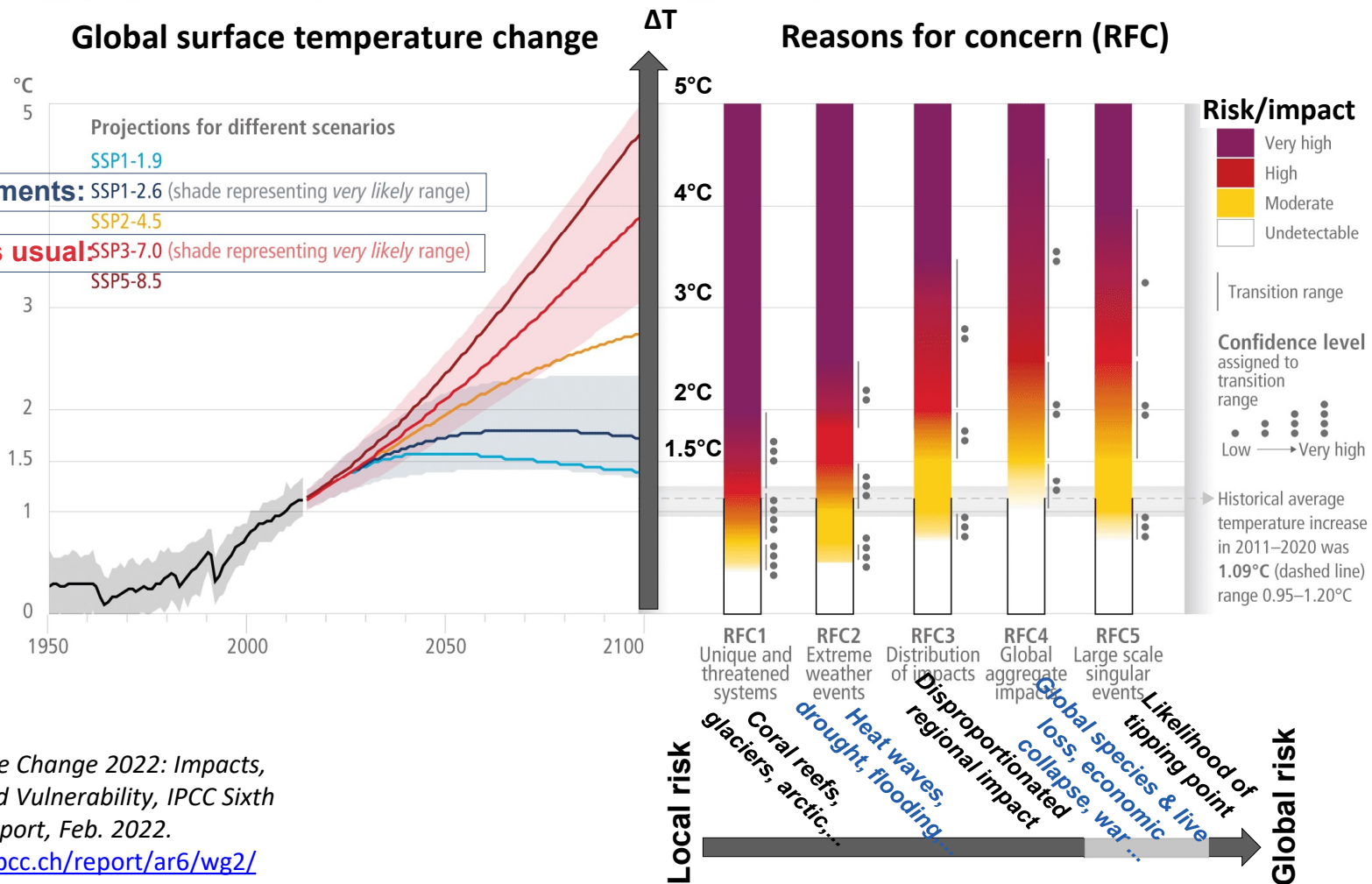
Paris agreements: SSP1-2.6 (shade representing very likely range)

Business as usual: SSP3-7.0 (shade representing very likely range)

Source: *Climate Change 2022: Impacts, Adaptation and Vulnerability, IPCC Sixth Assessment Report, Feb. 2022.*

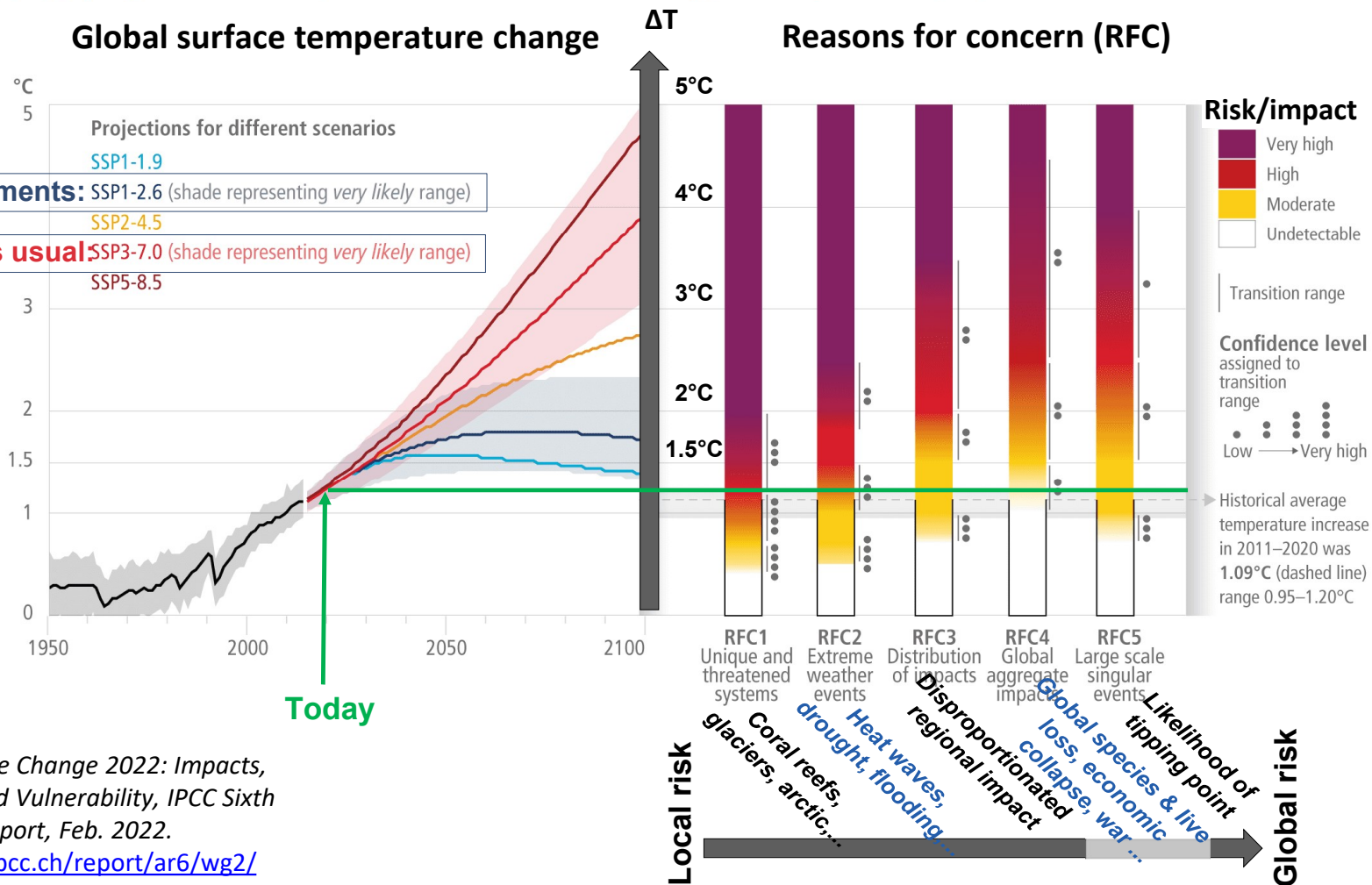
<https://www.ipcc.ch/report/ar6/wg2/>

Risks for increasing levels of global warming



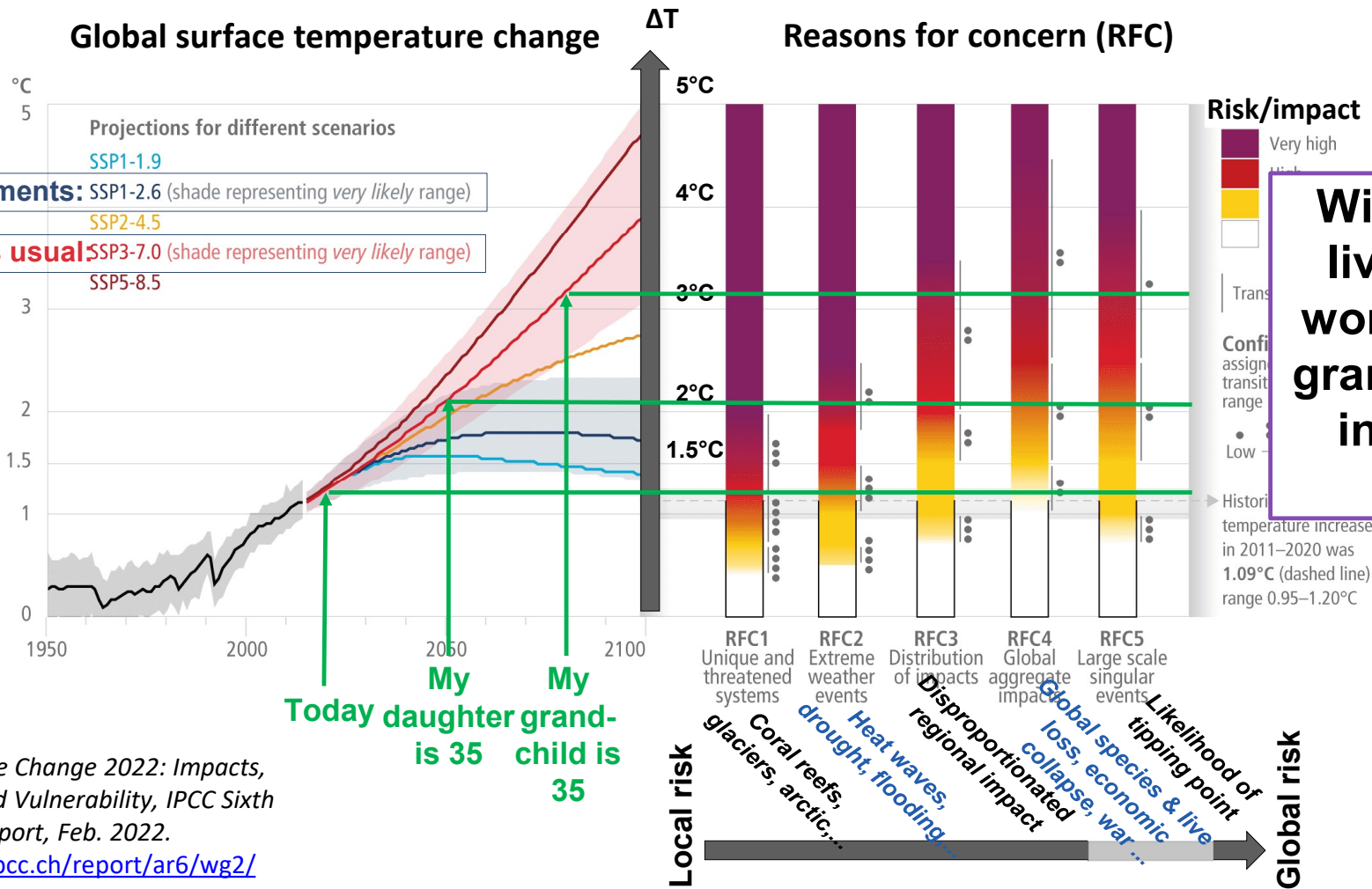
Source: *Climate Change 2022: Impacts, Adaptation and Vulnerability, IPCC Sixth Assessment Report, Feb. 2022.*
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Risks for increasing levels of global warming



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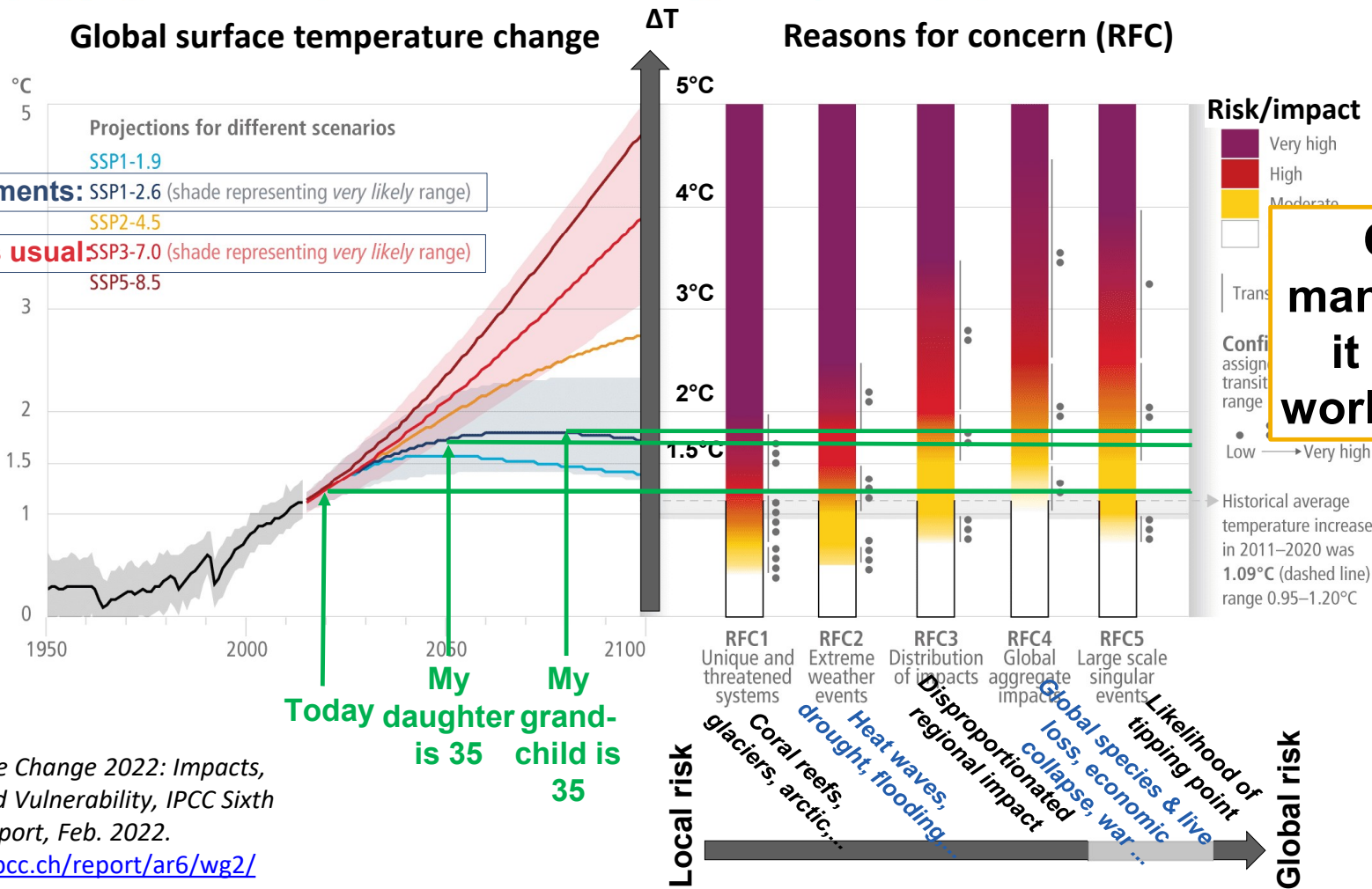
Risks for increasing levels of global warming



Will our kids live in a red world and our grand-children in a purple world ?

Source: *Climate Change 2022: Impacts, Adaptation and Vulnerability, IPCC Sixth Assessment Report, Feb. 2022.*
<https://www.ipcc.ch/report/ar6/wg2/>

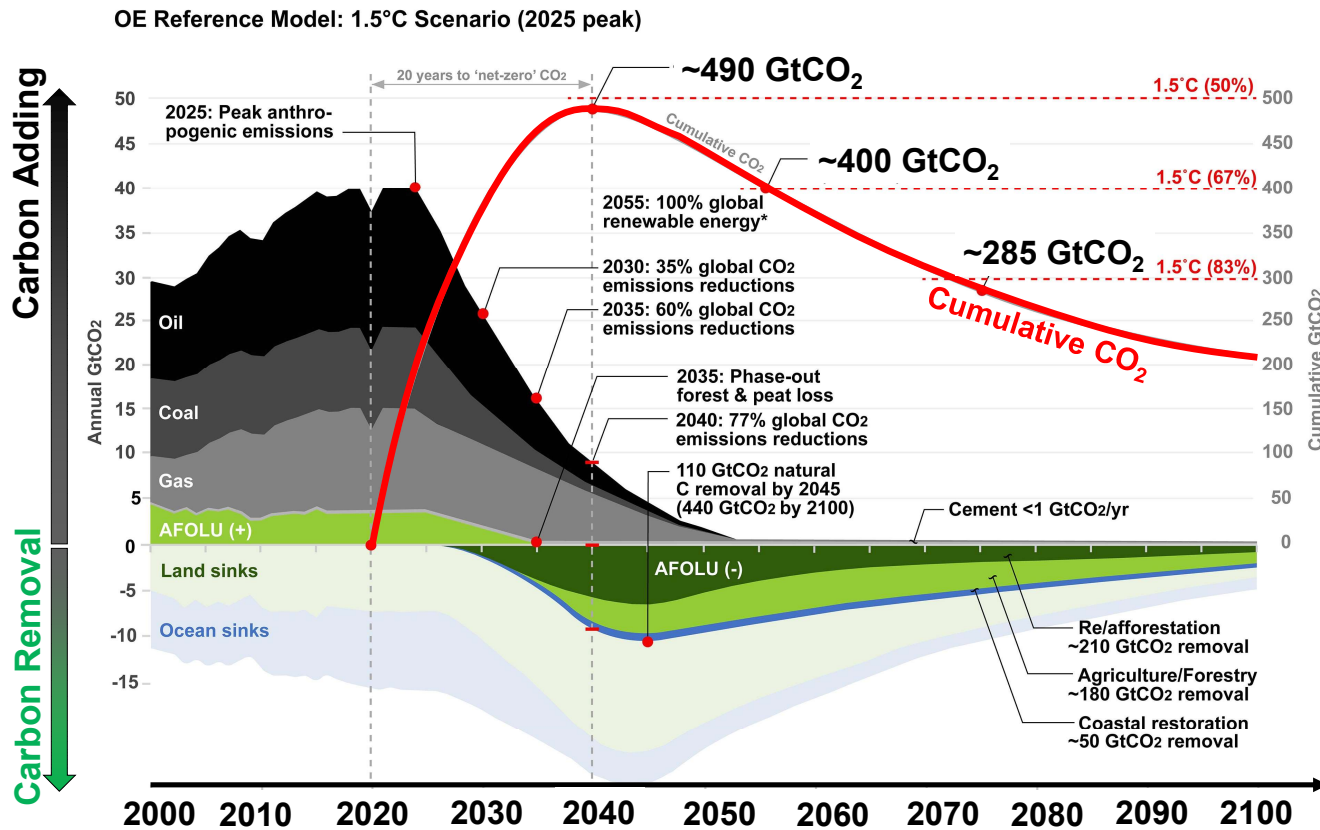
Risks for increasing levels of global warming



My Today daughter is 35
My grand-child is 35

Source: *Climate Change 2022: Impacts, Adaptation and Vulnerability, IPCC Sixth Assessment Report, Feb. 2022.*
<https://www.ipcc.ch/report/ar6/wg2/>

What it takes to keep global warming under control



Achieve within 30 years:

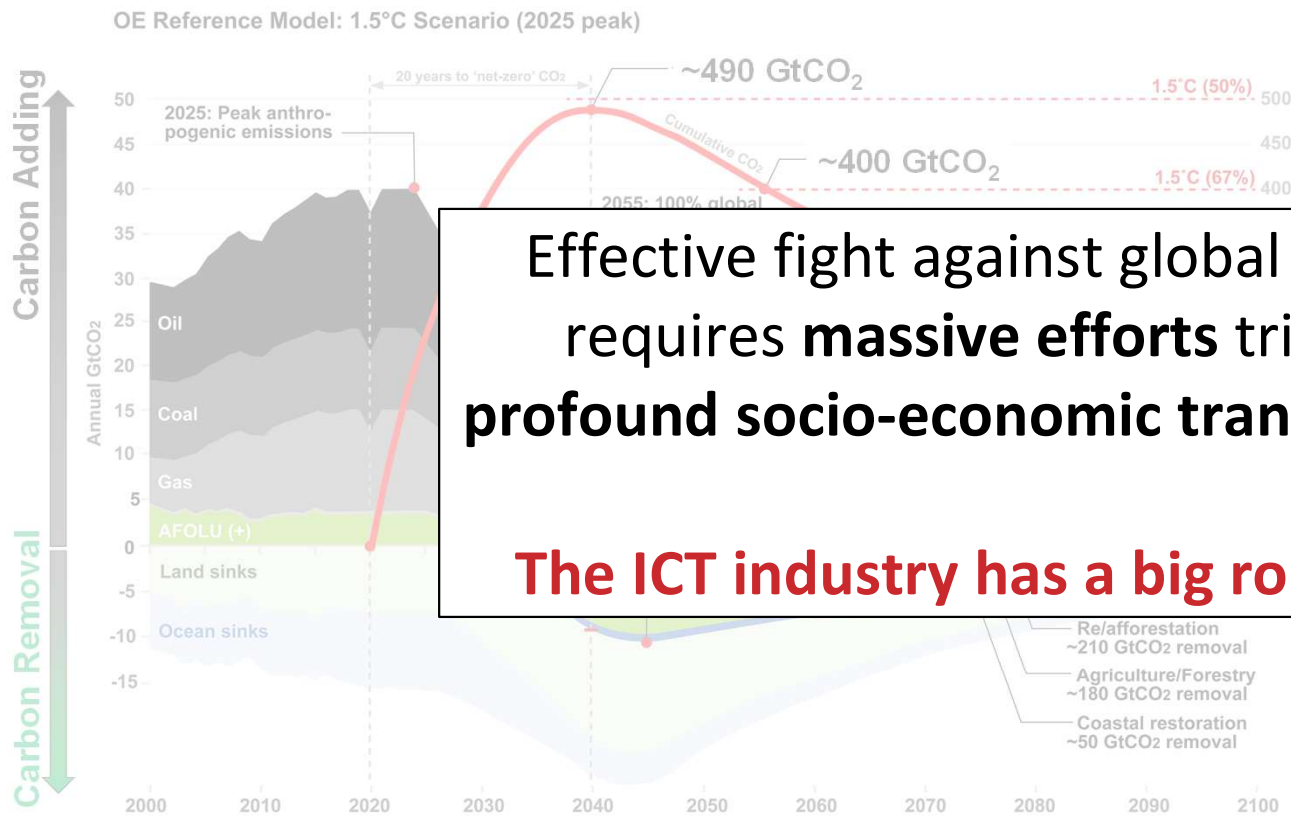
- Phase out fossil fuels => decarbonation of human activities, including industry
- 100% renewable energy
- 50% of lands and oceans protected and connected*
- Zero net emissions through regenerative agriculture

Source: <https://www.oneearth.org/below-1-5-c-a-breakthrough-roadmap-to-solve-the-climate-crisis/>

Climate model based on "Achieving the Paris Climate Agreement Goals", Springer 2019

AFOLU = Agriculture, Forestry & Other Land Use

What it takes to keep global warming under control



Effective fight against global warming requires **massive efforts** triggering **profound socio-economic transformation**

The ICT industry has a big role to play

This scenario requires to achieve within 30 years:

- Stop fossil fuels =>
- Reduction of human
- including industry
- Renewable energy
- lands and oceans
- protected and connected*
- Zero net emissions through regenerative agriculture

Source: <https://www.oneearth.org/below-1-5-c-a-breakthrough-roadmap-to-solve-the-climate-crisis/>

Climate model based on "Achieving the Paris Climate Agreement Goals", Springer 2019

AFOLU = Agriculture, Forestry & Other Land Use

The emissions of ICT industry in perspective

~ 36 GtCO_{2eq}/ year



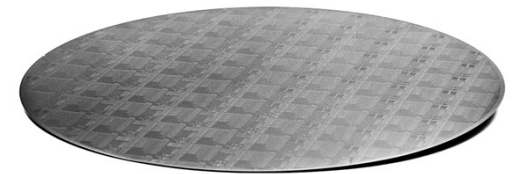
World-wide

~ 1.2 GtCO_{2eq}/ year

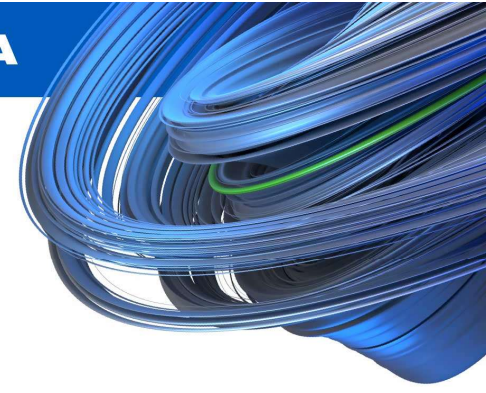


ICT Industry

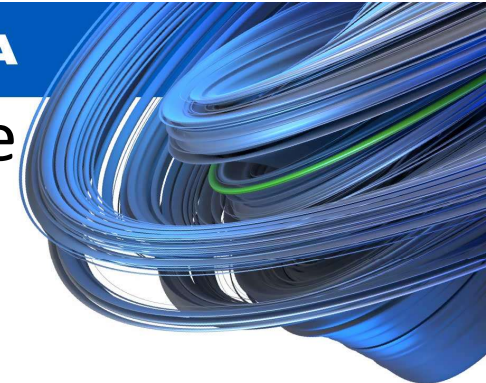
~ 100 MtCO_{2eq}/ year



Semiconductor manufacturing



The role of ICT industry in harnessing climate change



~ 36 GtCO_{2eq}/ year

Innovate products that help society and other industries along its transformative path:
Enablement vs. Rebound*

World-wide

~ 1.2 GtCO_{2eq}/ year

Decarbonate the **product use phase**

ICT Industry

~ 100 MtCO_{2eq}/ year

Reduce the environmental footprint of **product manufacturing**

Semiconductor manufacturing

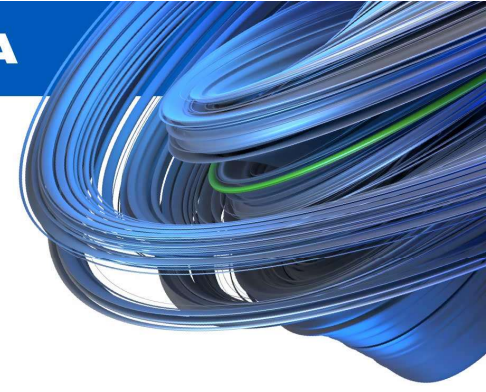
*See: Freitag et al., Patterns, 2021.

Bol et al. IEEE Proceedings -Design, Automation and Test in Europe, 2021.

L. Hilty and B. Aebischer, in ICT innovations for Sustainability. Springer, 2015.

SMARTer2030 - ICT solutions for 21st Century Challenges, GeSi, 2015.

The ICT industry is setting ambitious objectives



ICT industry to reduce greenhouse gas emissions by 45 per cent by 2030

ITU, GeSI, GSMA & SBTi set science-based pathway in line with Paris Agreement

ICT for Sustainable Development

Geneva, 27 February 2020

[Press Release \(itu.int\)](#)

PROGRESS TOWARDS NET ZERO

In recent years, big tech companies have been prominently leading the way on voluntary net zero ambition and progress; in many cases, goals are years ahead of the targets laid out by the IPCC.

<https://netzeroclimate.org/sectors/tech/>

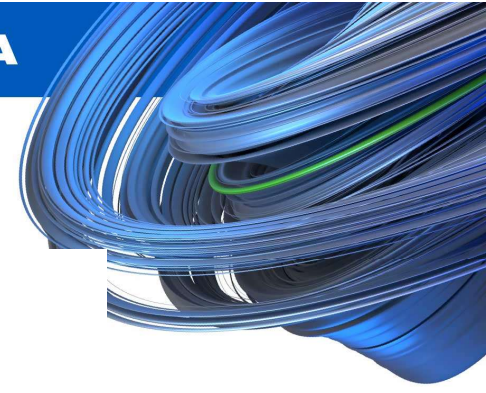


**SEMI ANNOUNCES
SEMICONDUCTOR CLIMATE
CONSORTIUM FOUNDING
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[SEMI Press release](#)

imec's climate ambition

Help the semiconductor industry achieving its objectives



Innovate products that help society and other industries along its transformative path

Decarbonate the **product use phase**

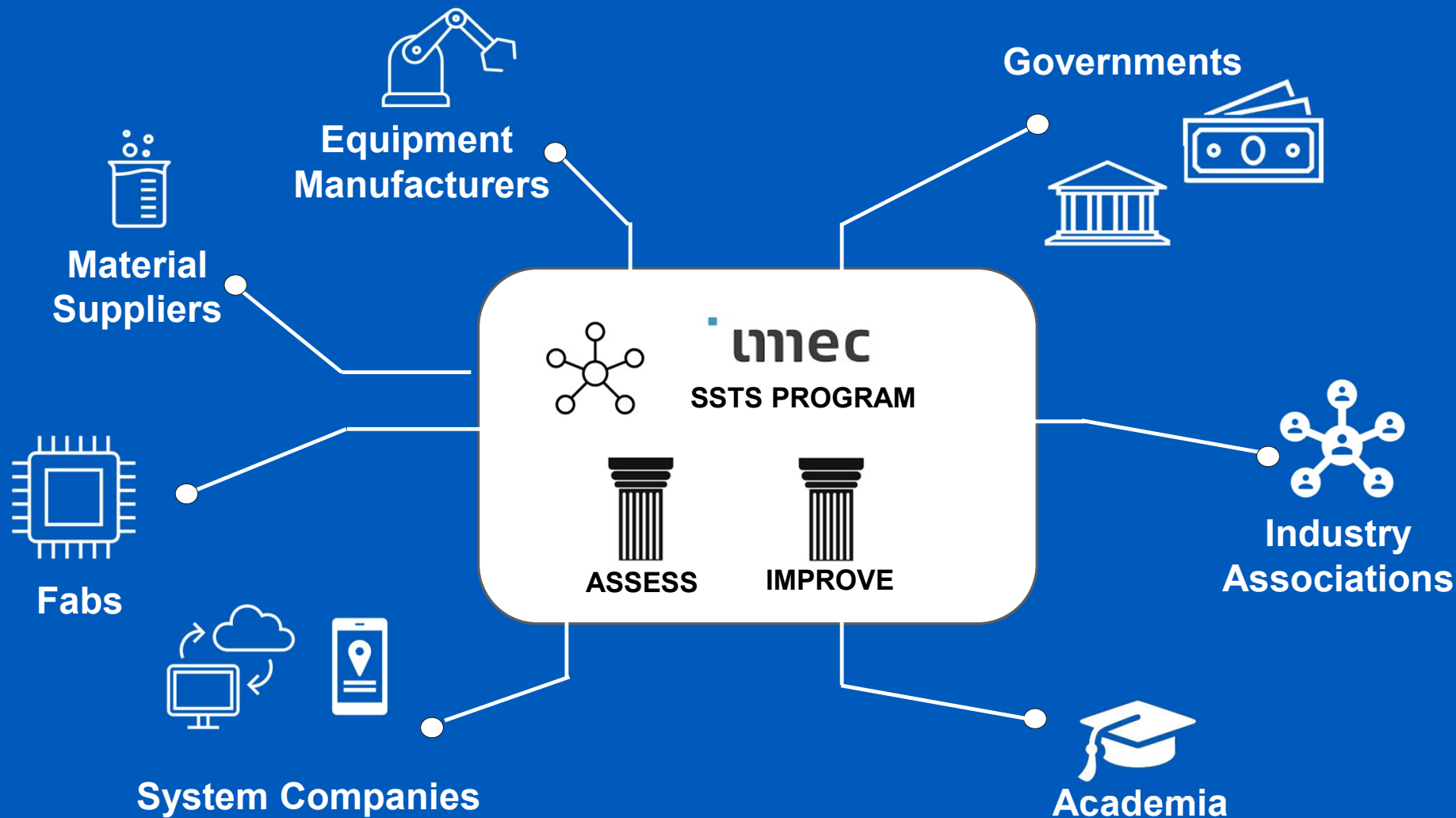
Reduce the environmental footprint of **product manufacturing**

imec programs

Performance Power Area & Cost (PPAC) driven innovation

Environmental driven innovation without sacrificing PPAC

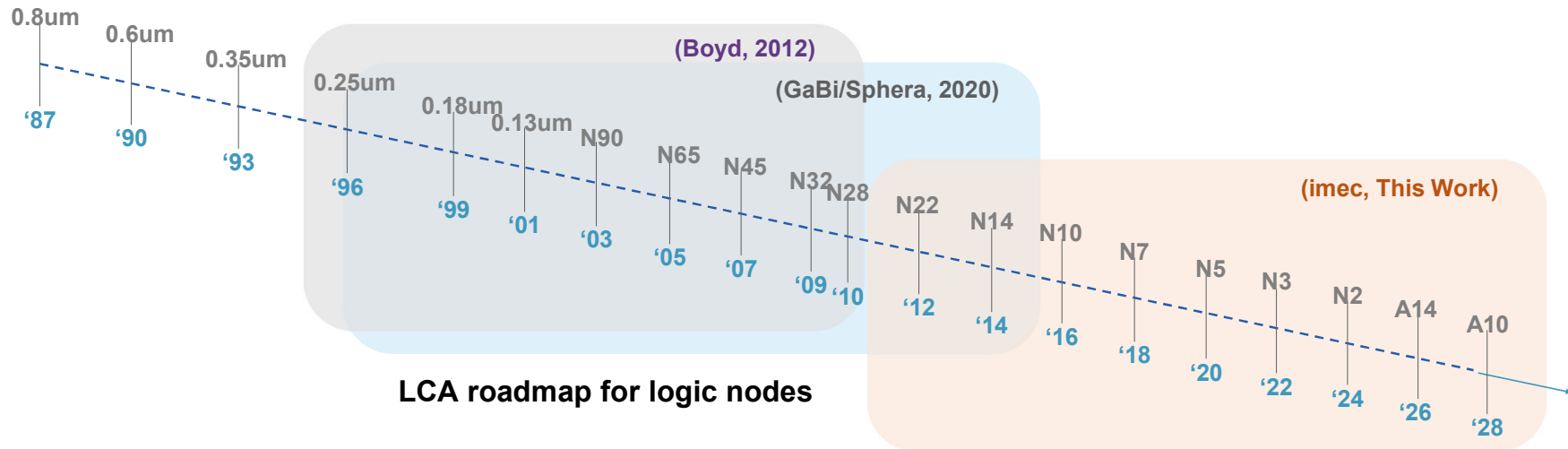
SSTS Program



SSTS Assess objective

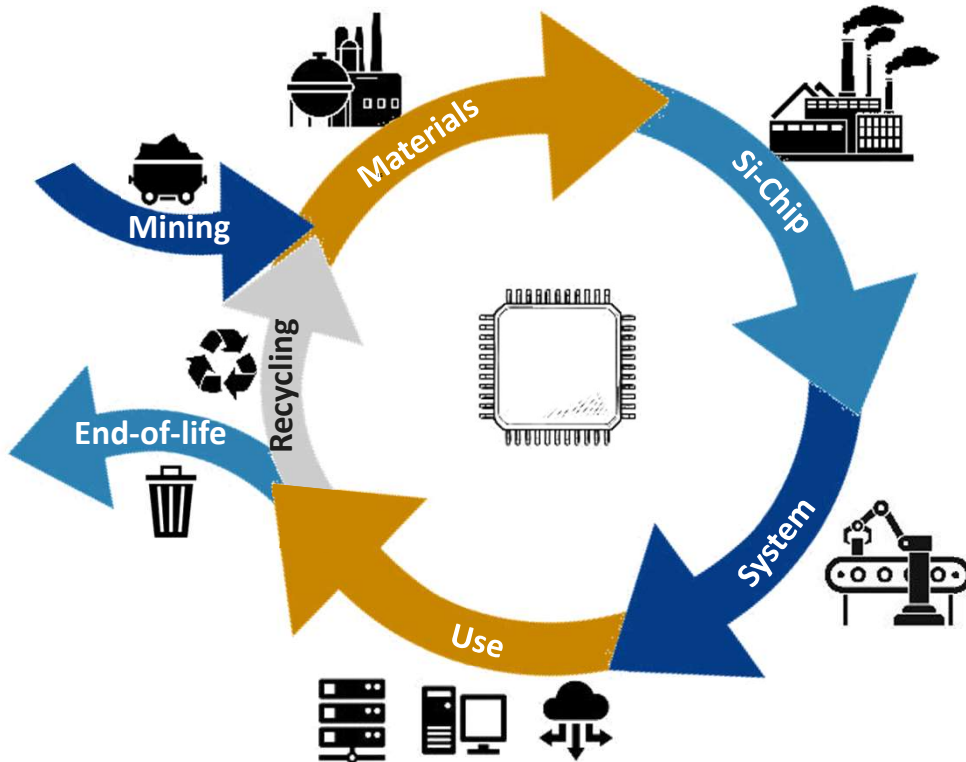
Quantify the **environmental footprint of making IC chips** in a High-Volume Manufacturing (HVM) semiconductor Fab

- Fill a **gap in life-cycle assessment** of the latest and future techs
- Identify **high impact problems** to focus Improve efforts
- Project the **future impact of IC chip manufacturing** and guide decision makers



The Life-Cycle of a Si-chip

Goal and scope of SSTS Assess



■ Product system

- Si chips from a generic 300mm HVM Fab:
 - Logic and Memory applications
 - Multiple (future) technology nodes

■ Functional Unit

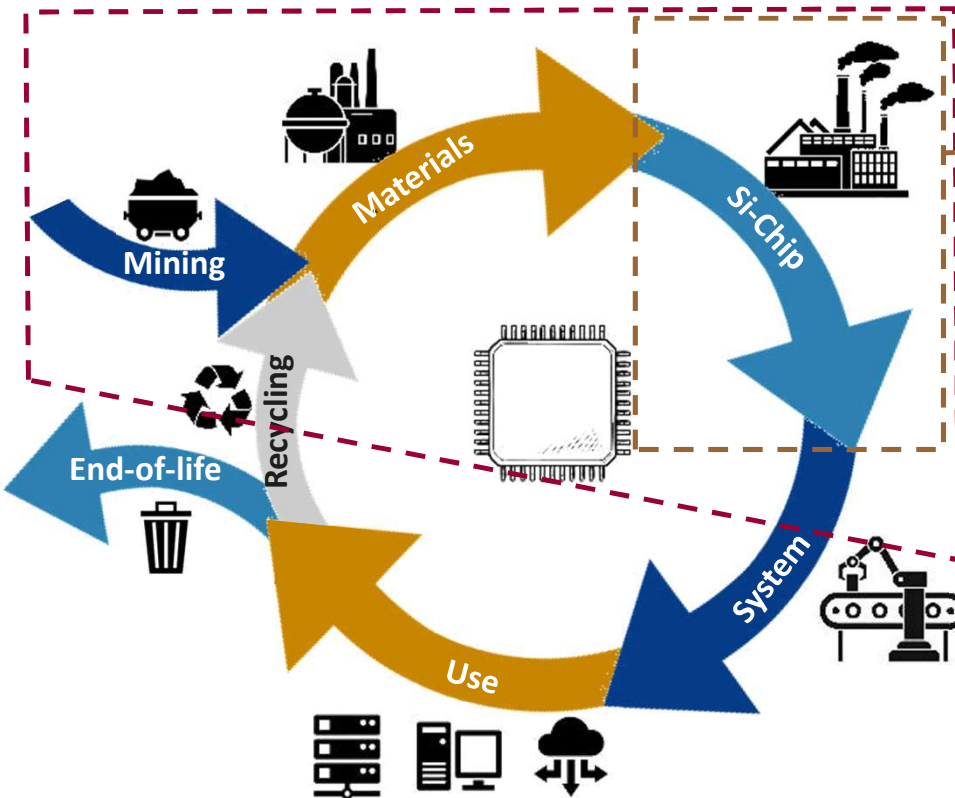
- For Manufacturing industry: “*per Wafer*”, “*per Mask Layer*”
- For IC Chip users: “*per functional die*”, “*per functional cm²*”

■ Impact categories

- *Climate Change*
- *Secondary Energy use (Electricity)*
- *Water usage*
- *Mineral usage and depletion potential*

The Life-Cycle of a Si-chip

Goal and scope of imec.netzero



- **System boundaries** – Two sets :

- **Gate-to-Gate semiconductor Fab.**

- Mainly PRIMARY data
- Flow includes: **Process Equipment, Utilities and Infrastructure** operation

- **Cradle-to-Gate Si-chip manufacturing.**

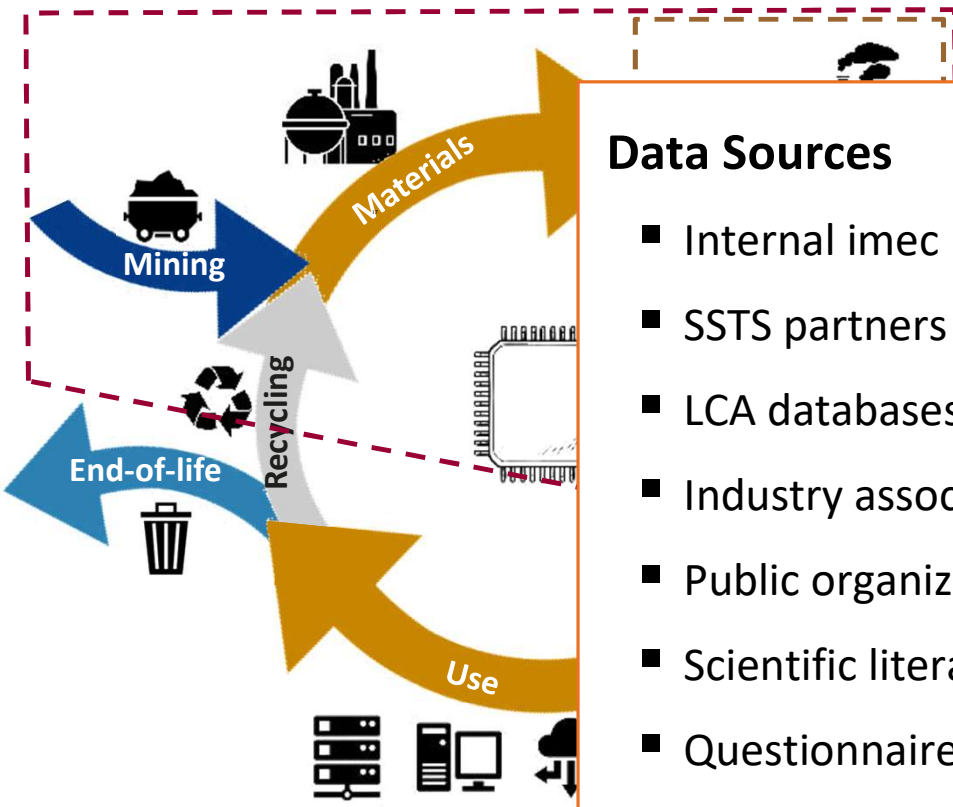
- Adding SECONDARY data
- **Recycling** considered at Fab level

- **Not included in present analysis**

- Equipment fabrication
- Infrastructure construction

The Life-Cycle of a Si-chip

Goal and scope of imec.netzero



Data Sources

- Internal imec
- SSTS partners
- LCA databases
- Industry associations: SEMI, ...
- Public organizations: IPCC, IEA, ...
- Scientific literature
- Questionnaire to supply chain

System boundaries – Two sets :

■ **Primary data** – Semiconductor Fab.

■ **Secondary data** –

■ **Process Equipment, Utilities**

■ **Structure operation**

■ **Si-chip manufacturing.**

■ **Secondary data**

■ **Considered at Fab level**

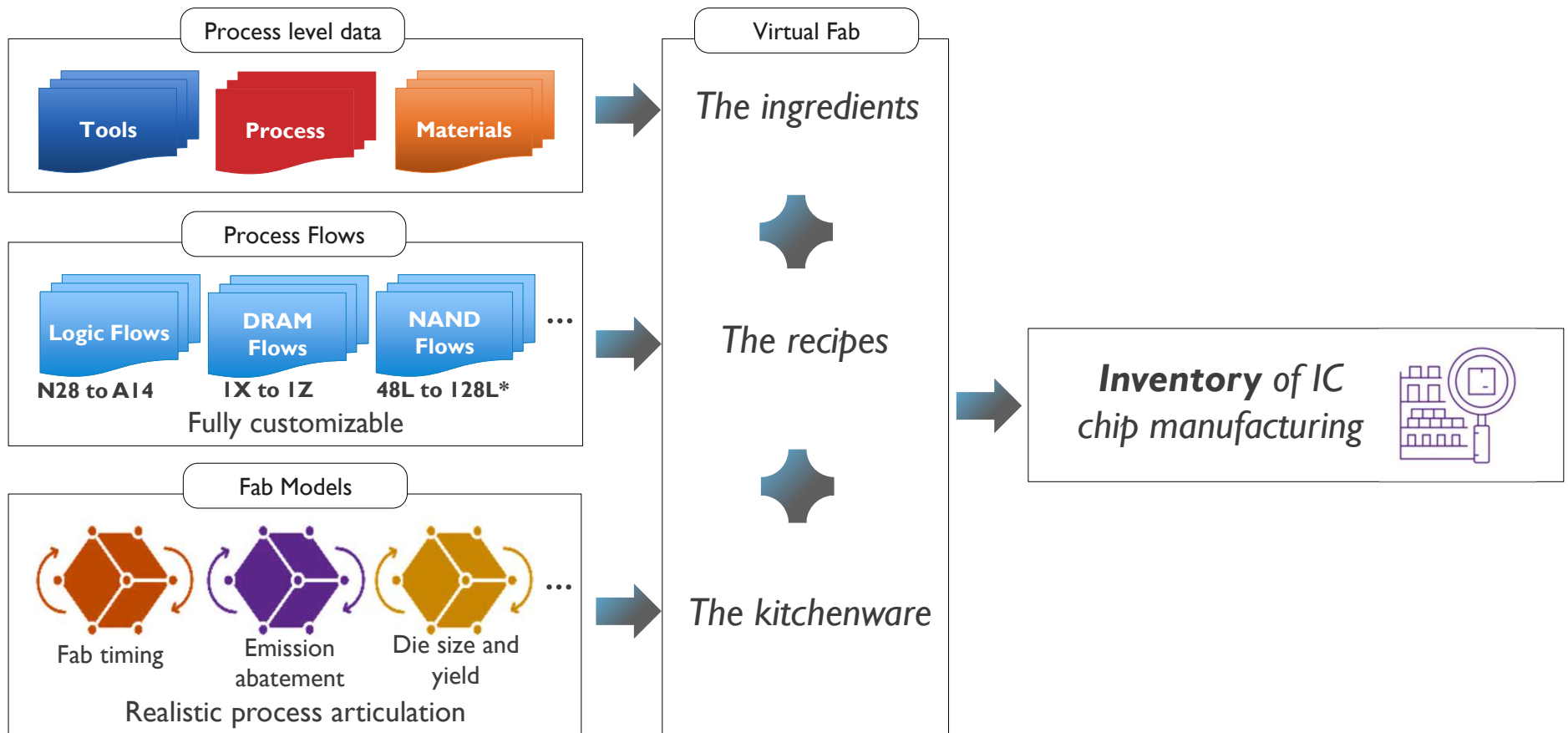
in present analysis

■ **abrication**

■ **Construction**

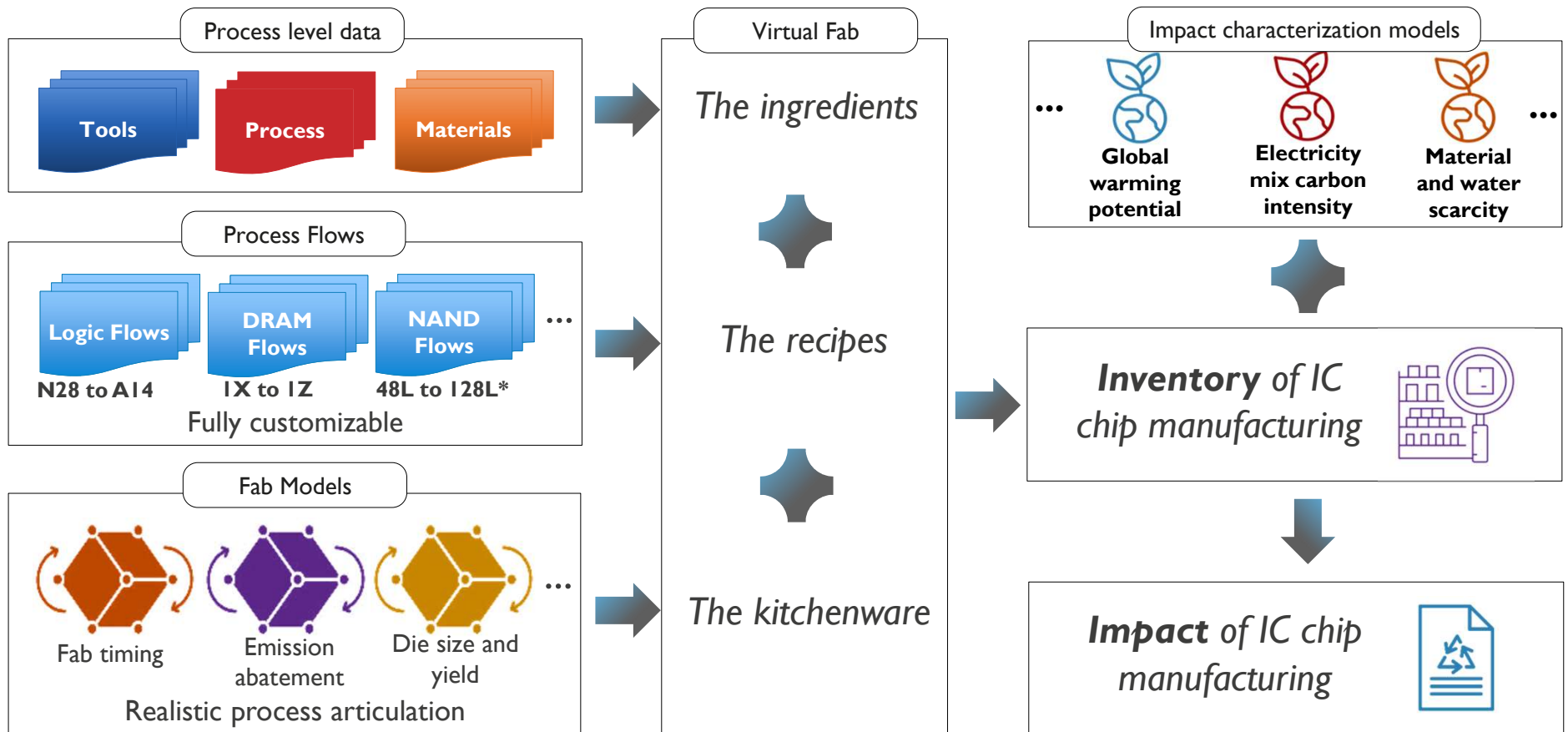
Gate-to-gate HVM Fab Life-Cycle Assessment

Bottom-up model implementation



Gate-to-gate HVM Fab Life-Cycle Assessment

Bottom-up model implementation

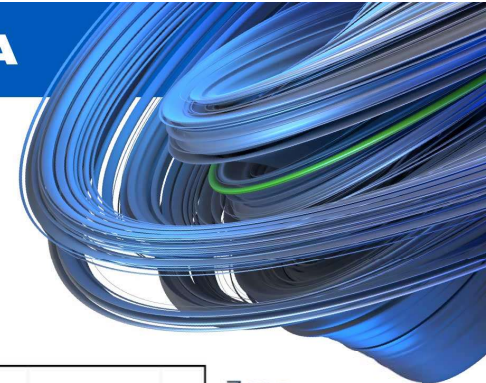


Studied Logic CMOS technologies and nodes



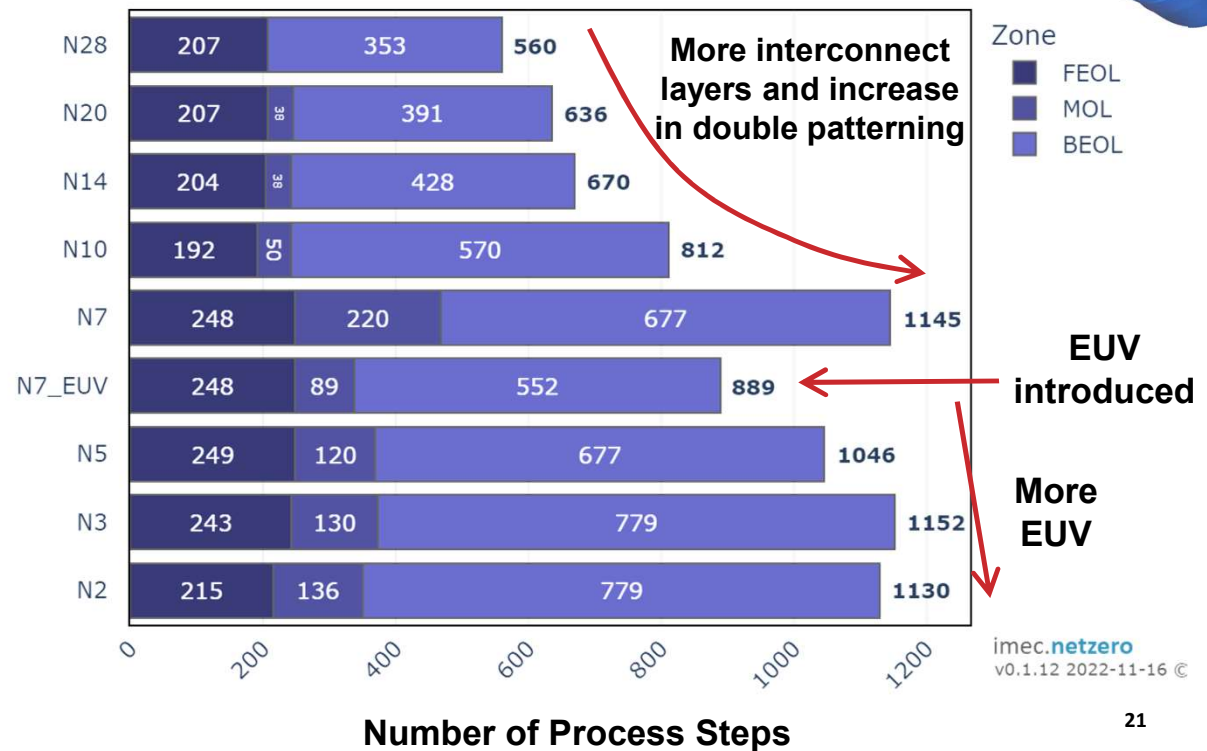
Technology Node	N28	N20	N14	N10	N7	N5	N3	N2	A14
Metal Pitch [nm]	90	64	64	48	40	28	22	21	18
Device structure	<p>Planar</p>		<p>FinFETs</p>					<p>Nanosheets</p>	
Standard cells # tracks	9T	9T	9T	7.5T	6.5T	6T	6T	5T	5T
Scaling boosters			Self Aligned Gate Contact			Metal Gate Cut		Backside power delivery	
Lithography	Immersion (ArFi)							EUV	

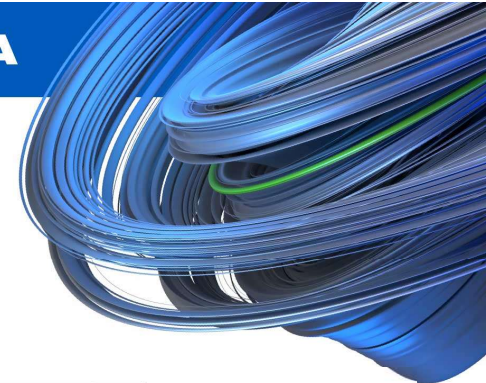
Nodes based on imec process flow are generic but representative of foundry nodes.



Complexity Increase of a Mobile SoC

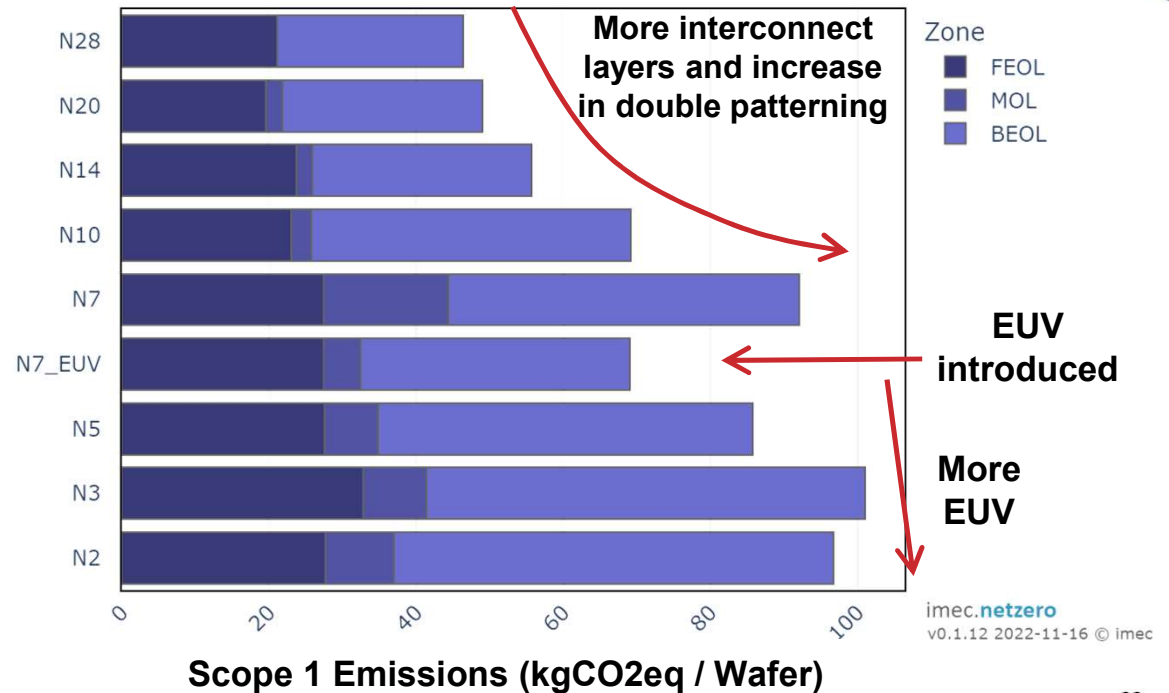
- Increase in Complexity node to node where BEOL interconnects dominate
- Introduction of EUV slows down the increase in complexity:
 - Less multi-patterning DUV immersion steps
 - Less deposition, Dry-Etch, Wet-Clean, Metrology steps





Direct Emissions (Scope 1)

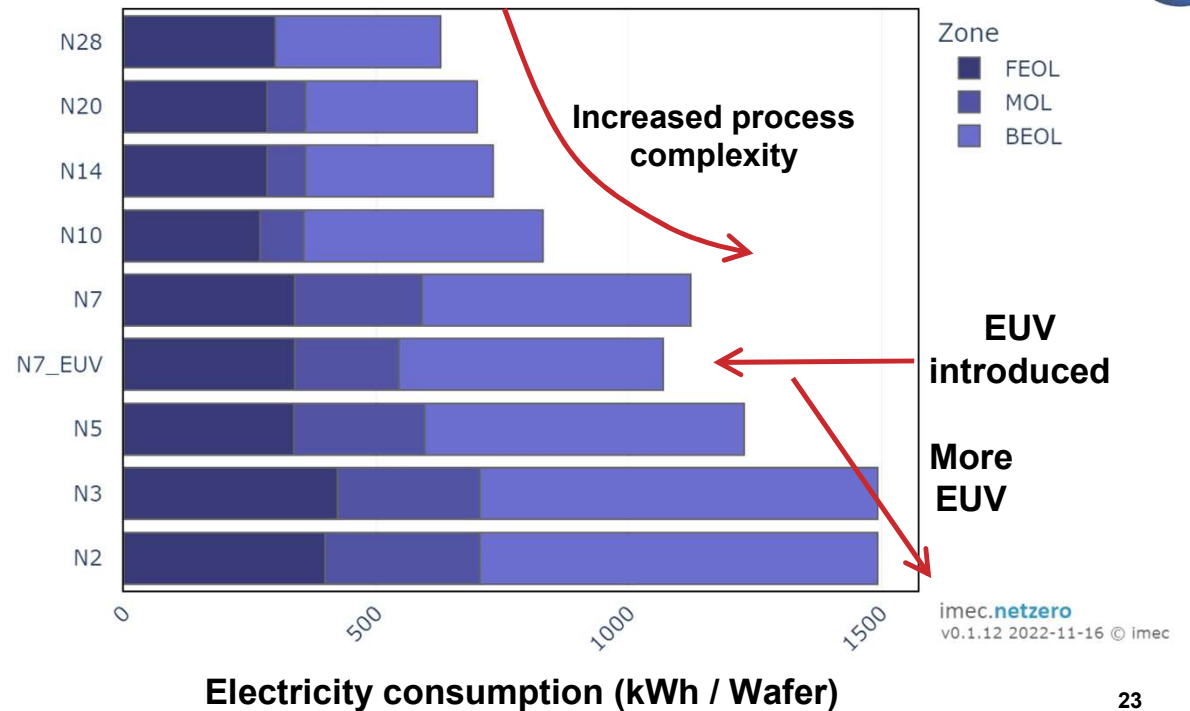
- Process gases are potent Greenhouse gases => **Deposition and Etch** contribute strongly to direct emissions
- Multi patterning use many repeats of deposition and etch ⇔ **By reducing complexity, EUV keeps direct emissions under check**



Tier 2C Abatement (2019 Refinement to the 2006 IPCC Guidelines for National Greenhouse Gas Inventories) and GHG global warming potential (IPCC AR6).

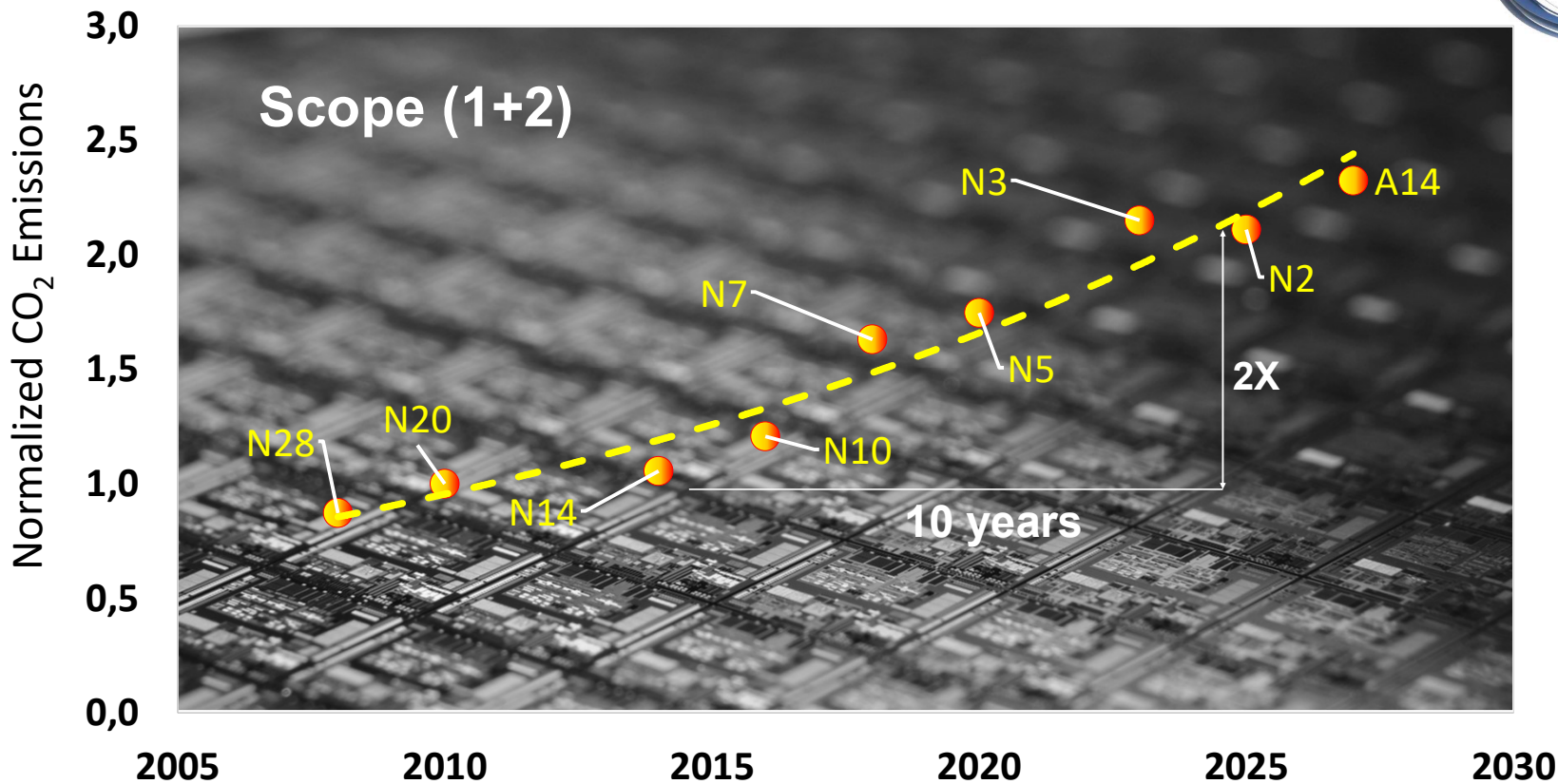
Electricity consumption

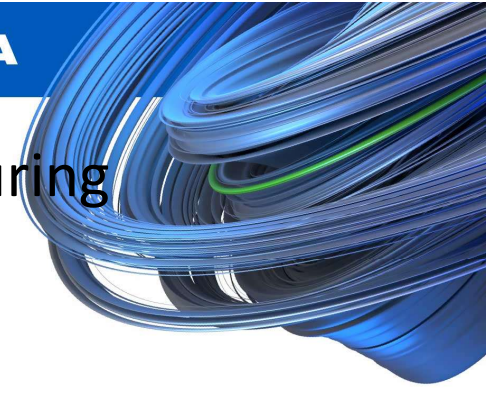
- Increase in process complexity directly leads to increased electricity consumption
 - Introduction of EUV leads to:
 - **Reduce in process complexity**
 - **Increased electricity consumption** of the litho process area
- These two effect counteract each other leading to a continued increase.



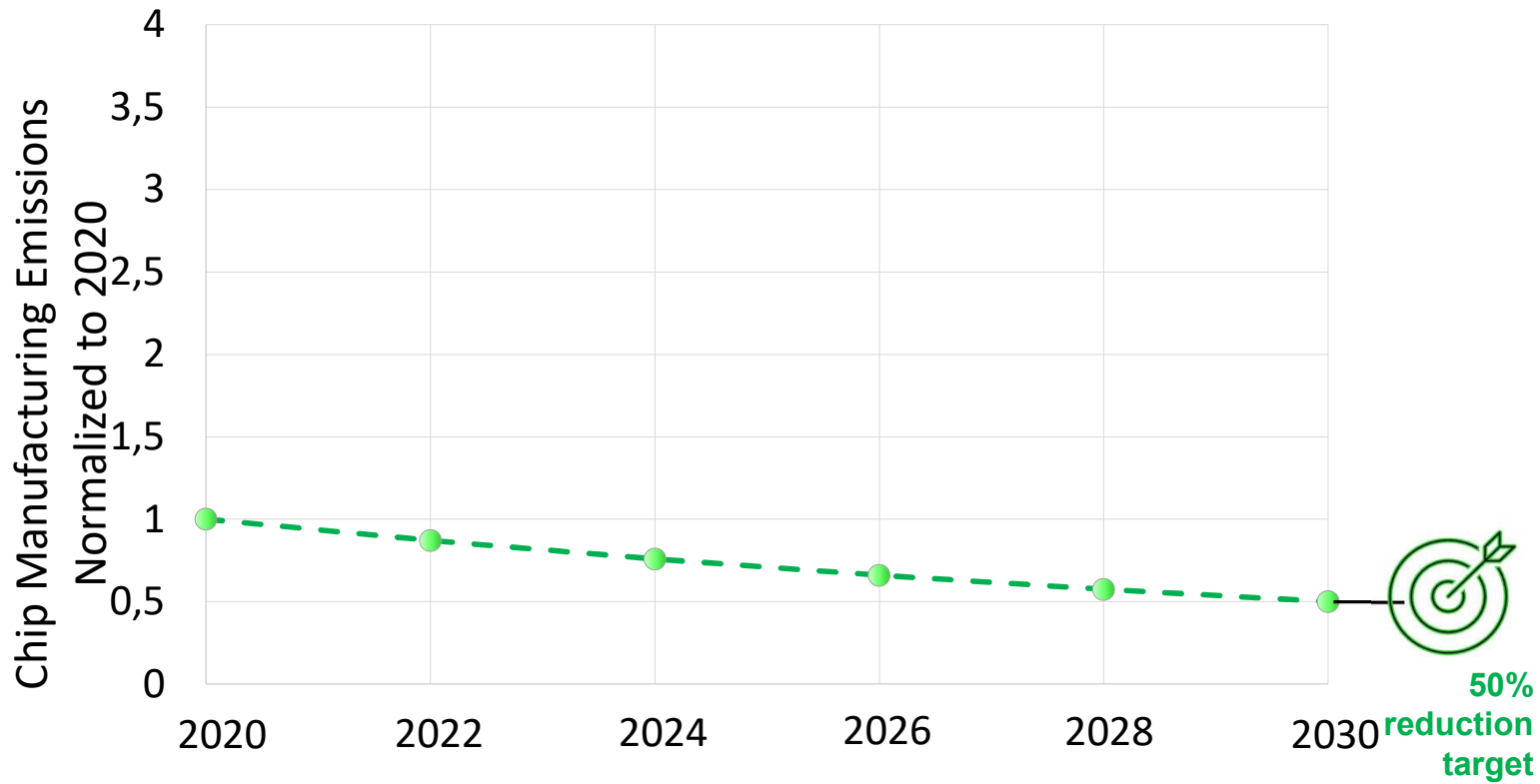
Utility electricity consumption modelled using SEMI S23 standard.

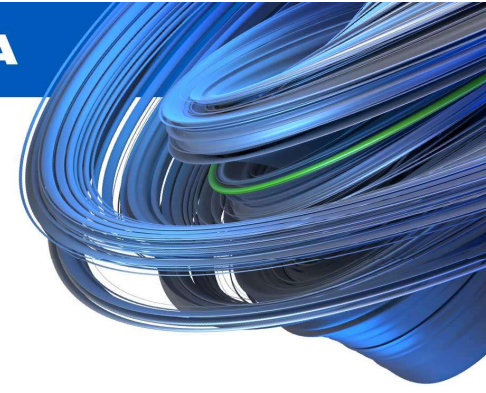
Total Emissions are on the rise



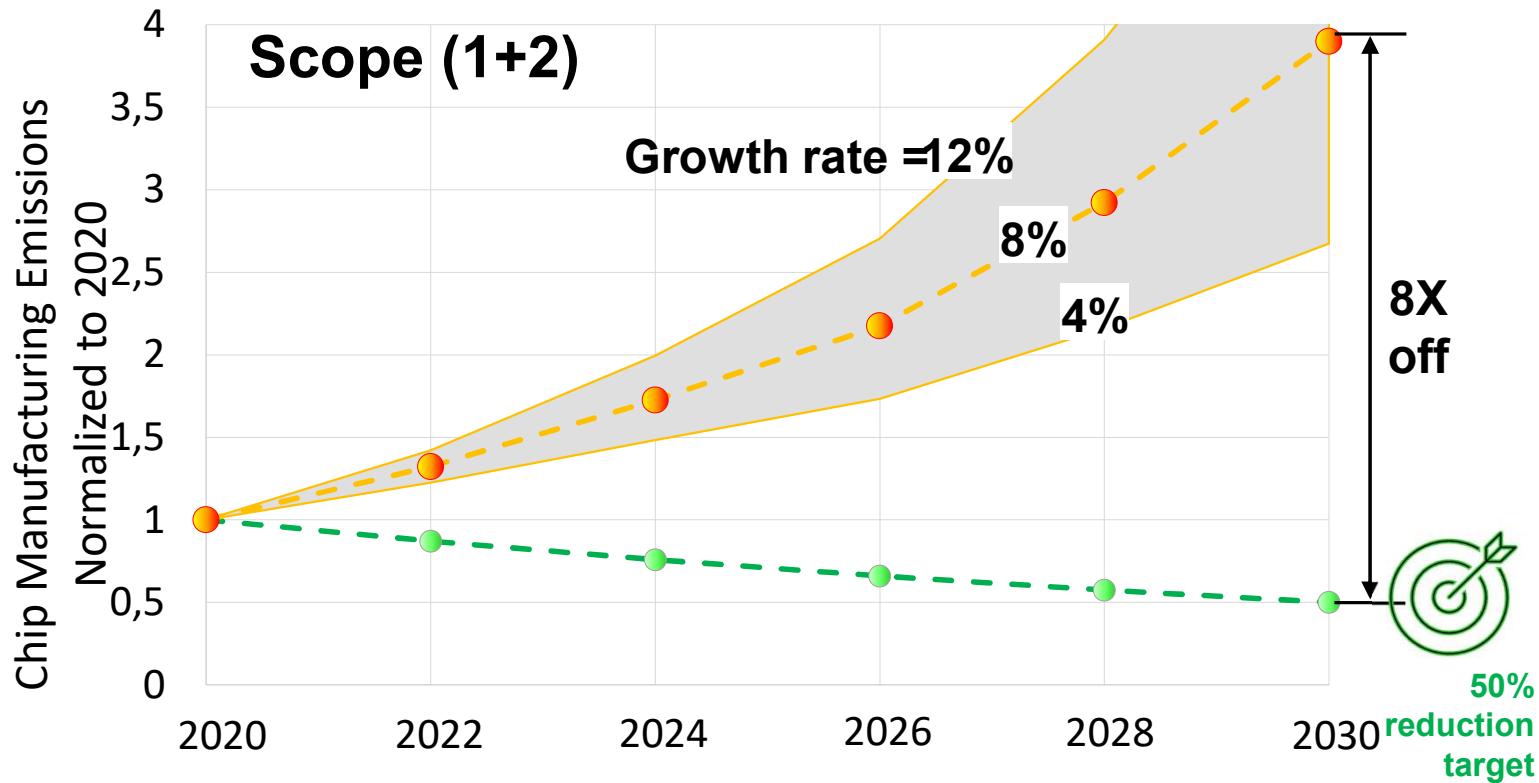


Ideal climate impact scenario for Semiconductor Manufacturing





“Do Nothing” Scenario for Semiconductor Manufacturing



Projection includes:

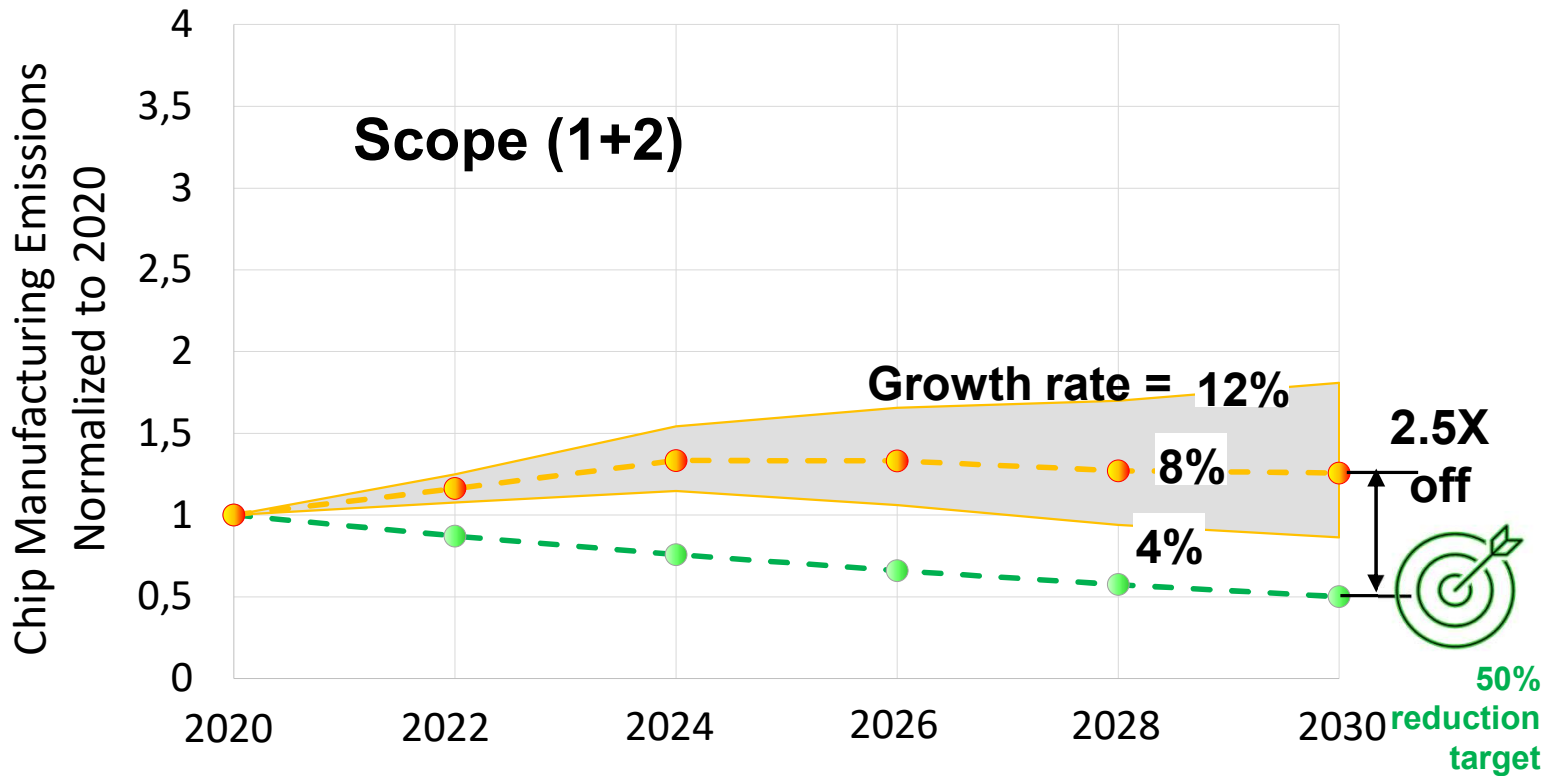
- Evolution of technology mix
- Increase in technology complexity
- ICT Market growth

Electricity mix and abatement not evolving.

Constant electricity mix (0.49 kCO₂eq/kWh), Tier 2C Abatement (2019 Refinement to the 2006 IPCC Guidelines for National Greenhouse Gas Inventories) and GHG global warming potential (IPCC AR6). Volume technology mix from IBS “Foundry Market Trends and Strategic Implications” Vol 30, N 12, Dec 2021. Logic nodes only.



With Renewable Energy and State-of-the-Art GHG Abatement



Projection includes:

- Evolution of technology mix
- Increase in technology complexity
- ICT Market growth
- **Renewable energy deployment**
- **State-of-art abatement from 2026 onwards**

Adding to previous slide: Renewable Energy deployment according to IEA and abatement according to IPCC assumed for the years 2020-2024, State-of-the art Abatement from 2026.



Call to Action



Adopt 50% emissions reduction this decade as target



Must-do for fabs: renewables, best abatement

- New research: materials, equipment, fabs, device makers



Report transparently including scope 3



Share best practices openly

Thank You

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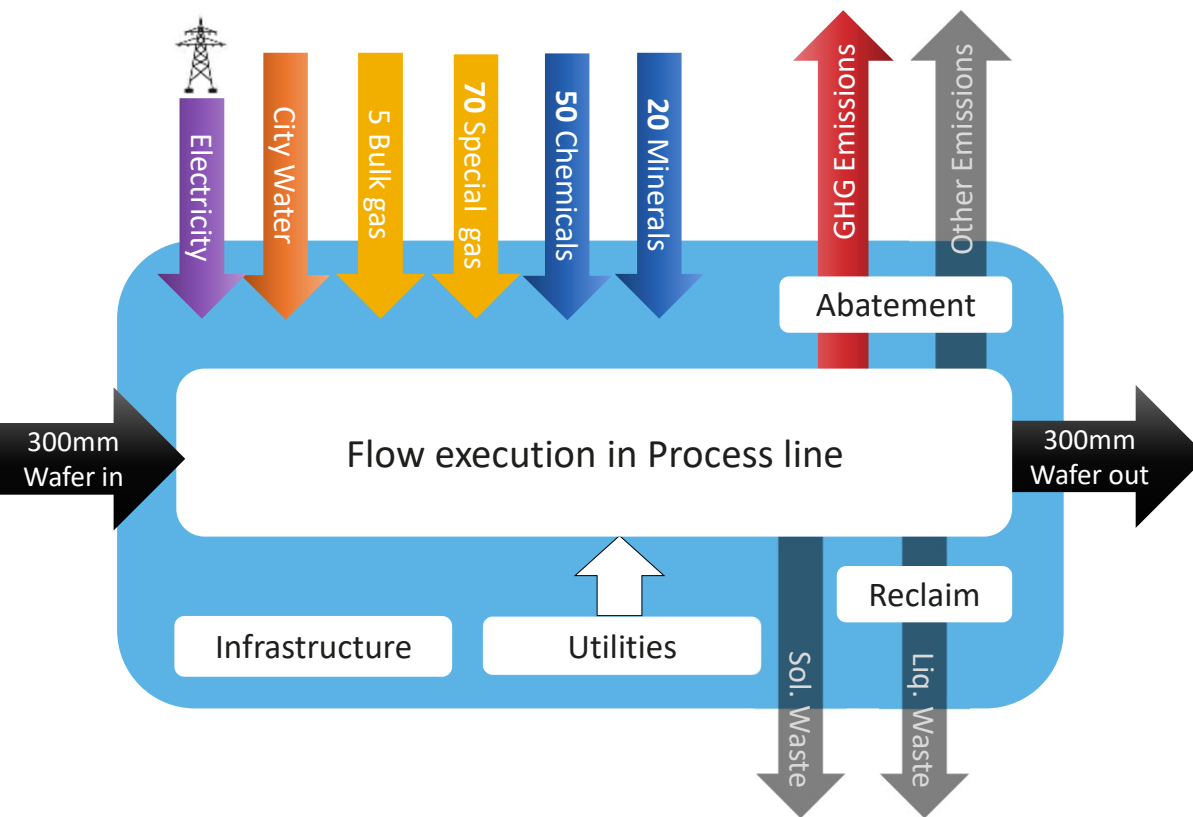
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ANNEX



Gate-to-gate HVM Fab Life-Cycle Inventory



Material and Energy input flows
Flow of material/energy i :

$$Flow\ per\ wafer\ i = \sum_p^{Full\ process\ flow} \frac{Resource\ consumption_{i,p}}{Process\ Throughput_p}$$

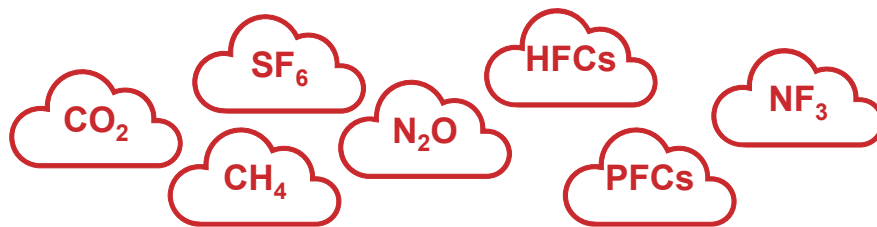
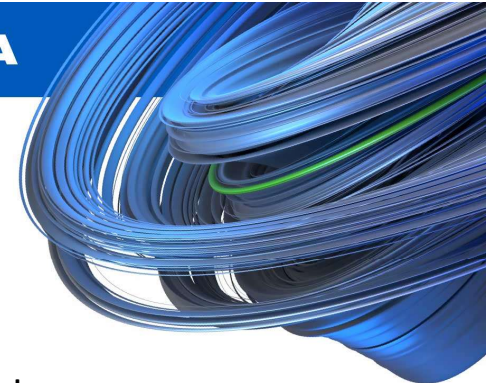
Utilities: Consumption tracked at process step level.
Infrastructure: Top-down approach.

Direct emissions
 Direct emissions of GHGs are calculated by modelling **tool utilization** and **abatement**.
 The direct emission of other gases is currently not tracked.

Output wastes
 The release of waste streams is currently not tracked.

The Greenhouse Gas Protocol: Scopes 1-3

The case for Semiconductor Manufacturing of Integrated Circuits



Scope 2
Indirect

Scope 1
Direct

Scope 3
Indirect

- Included in our work:
 - 1. Process Gas Emissions**
 - 2. Electricity**
 - 3. Material Sourcing (in progress)**



**Purchased Electricity
for own use**



**Fuel Combustion,
Process Gas Emissions
Company owned Vehicles**



**Production of
Purchased
Materials**

Use

**Waste
Disposal**

**Business
Travel**